



GP/1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: YOUNG-HOON PARK  
SERIAL NUMBER: 09/848,577  
FILED: May 3, 2001  
FOR: REACTOR FOR DEPOSITING  
THIN FILM ON WAFER

)  
) Group Art Unit:  
) 1763  
)  
) Examiner:  
) Karlaa Moore.  
)  
)

#17. B  
12/19/02  
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Commissioner of Patents and Trademarks  
Washington, D.C. 20231

RECEIVED

DEC 17 2002

TC 1700

Dear Sir:

This amendment with remarks is submitted in response to an Office Action dated September 11, 2002. Applicant requests reconsideration of the outstanding rejection in view of the following remarks and amendments.

AMENDMENT

IN THE CLAIMS:

Please enter the following newly added claims.

18. (Newly Added) The thin film deposition reactor of claim 1, wherein an interval between a center of the diffusion plate and the wafer block is different from an interval between edges of the diffusion plate and the wafer block.

I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO:  
ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D. C. 20231

ON 09 DEC. 2002  
DATE OF DEPOSIT  
Daniel Drexler  
(TYPED OR PRINTED NAME OF PERSON MAILING PAPER OR FEE)  
09 DEC. '02  
SIGNATURE DATE

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(b) 11/19/02  
conclude